IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

BEFORE THE PATENT TRIAL AND APPEAL BOARD

APPLIED MATERIALS, INC.,

Petitioner

v.

OCEAN SEMICONDUCTOR LLC,

Patent Owner.

Case IPR: Unassigned U.S. Patent No. 6,836,691

PETITION FOR *INTER PARTES* REVIEW OF U.S. PATENT NO. 6,836,691

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EXHIBIT LIST

Exhibit No.	Description
1001	U.S. Patent No. 6,836,691 ("'691 patent")
1002	Declaration of Miltiadis Hatalis, Ph.D.
1003	Curriculum Vitae of Miltiadis Hatalis, Ph.D.
1004	File Wrapper for the '691 patent
1005	Funk et al., U.S. Patent No. 7,123,980 (filed Mar. 23, 2005; issued Oct. 17, 2006) ("Funk")
1006	Funk, U.S. Provisional Application No. 60/414,425 (filed Sept. 30, 2002; expired July 19, 2004)
1007	Funk et al., International Publication No. WO 2004/031875 (filed Sept. 25, 2003; published Apr. 15, 2004)
1008	Stoddard et al., U.S. Patent No. 6,587,744 (filed June 20, 2000; issued July 1, 2003)
1009	File Wrapper for Funk
1010	Roger E. Bohn and Christian Terwiesch, <i>The Economics of Yield-Driven Processes</i> , J. Operations Management, 18: 41-59 (1999)
1011	Robert C. Leachman and David A. Hodges, <i>Benchmarking Semiconductor Manufacturing</i> , IEEE Transactions on Semiconductor Manufacturing, 9: 158-69 (1996)
1012	Gardner, et al., <i>Equipment Fault Detection Using Spatial Signatures</i> , IEEE Transactions on Components, Packaging, and Manufacturing Technology—Part C, 20: 295-304 (1997)
1013	John McGehee, <i>The MMST Computer-Integrated Manufacturing System Framework</i> , IEEE Transactions on Semiconductor Manufacturing, 7: 107-16 (1994)
1014	Jula, P. et al., Comparing the Economic Impact of Alternative Metrology Methods in Semiconductor Manufacturing, IEEE Transactions on Semiconductor Manufacturing, Vol. 15, No. 4 (November 2002)



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1015	Richard J. Markle and Elfido Coss, Jr., <i>Data requirements and communication issues for advanced process control</i> , J. of Vacuum Sci. & Tech. A 19, 1241 (2001).
1016	Musacchio, J., et al., <i>On the Utility of Run to Run Control in Semiconductor Manufacturing</i> , IEEE International Symposium on Semiconductor Manufacturing Conference Proceedings, D-9–D-12 (1997)
1017	Jerry A. Stefani and Mike Anderson, <i>Practical Issues in the Deployment of a Run-to-Run Control System in a Semiconductor Manufacturing Facility</i> , Proc. SPIE 3742, Process and Equipment Control in Microelectronic Manufacturing, 52-64 (April 23, 1999)
1018	Gabriel G. Barna, <i>APC in the Semiconductor Industry, History and Near Term Prognosis</i> , IEEE/SEMI 1996 Advanced Semiconductor Manufacturing Conference and Workshop. Theme-Innovative Approaches to Growth in the Semiconductor Industry. ASMC 96 Proceedings, 364-69 (1996)
1019	Limanond, S., et al., <i>Monitoring and Control of Semiconductor Manufacturing Processes</i> , IEEE Control Systems Magazine, 18:46-58 (1998)
1020	Ison, A.M., et al., Fault Diagnosis of Plasma Etch Equipment, IEEE International Symposium on Semiconductor Manufacturing Conference Proceedings (1997)
1021	Mark Melliar-Smith and Alain C. Diebold, <i>Metrology Needs for the Semiconductor Industry Over the Next Decade</i> , AIP Conference Proceedings 449, 3 (1998).
1022	Chris J. McDonald, New tools for yield improvement in integrated circuit manufacturing: can they be applied to reliability?, Microelectronics Reliability 39 (June 1999)
1023	Handbook of Thin Film Deposition Process and Technologies (2nd Ed. 2002); Chapter 6 Keefer, M. et al., "The Role of Metrology and Inspection in Semiconductor Processing"



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